An apparatus, system, and method are disclosed for low cost high resolution chemical detection. The apparatus includes two outer sealing bodies with flow channels etched into the bodies. Two gas chromatography (GC) columns are between the outer bodies, with a valve that switches flow regimes from series flow through the two GC columns to sample flowing directly to each GC column. The flow regimes are achieved with a single pump or dual pumps, and with one to three flow restrictions. The apparatus includes a precollection tube for concentrating chemicals of interest from the sample, and a sample switching valve and sampling pump to switch the sample flow from concentrating sample to delivering concentrated sample. The apparatus includes an engineered leak to equalize flow between a sample channel and a detector circuit. The sample channels may have impermeable inserts allowing the apparatus to measure chemicals in the parts-per-billion range.
Fig. 1

Sensor

Controller

Temperature control module

Sample introduction module

Signal processing module

GC column switching module

Similarity sequencing module

Noise-filtering module
Fig. 2A

- Ambient temperature
- Set of temperature-based elution data
- Elution data samples
- System Z-transform
- Plurality of noise wavelets
- Controller 104
  - Temperature control module 106
  - GC column switching module 108
  - Sample introduction module 110
  - Similarity sequencing module 112
  - Signal processing module 114
  - Noise-filtering module 116
- GC target temperature
- Heating element command
- First/second flow regime command
- Concentration/desorption flow regime command
- Sequenced data
- Input data (from Z-transform)
- Peak identifications
Controller 104

Specified temperature 226

Internal standard delivery module 228

Heat preconcentration command 230

Known chemical release 232

Calibration module 234

Known chemical elution data 236

Fig. 2B
Noise wavelet 1

Noise wavelet 2

Noise wavelet 3

Fig. 15
1600

Start

1602

Bending a tube into a GC column

1604

Crimp the end of the GC column

1606

Store and transport the column

1608

Cut off the crimped end of the column

1610

Install the GC column into a GC sensor

End

Fig. 16
1700 Start

1702 Pack a preconcentration material into a GC sensor

1704 Heat the preconcentration material to a specified temperature

1706 Track the elution of a known byproduct

1708 Compare the elution time to a known standard elution time

End

Fig. 17
1800 Start
1802 Mix a microsphere-adhesive slurry
1804 Place some slurry at one end of a slot
1806 Insert an offset rod
1808 Pack in preconcentration material
1810 Insert another offset rod
1812 Place some slurry at the other end of the slot
End

Fig. 18
Start

1902 Store elution versus temperature data

1904 Detect ambient temperature

1906 Select a target temperature

1908 Heat GC columns to the target temperature

End

Fig. 19
Is a variable time step sampling rate available? YES

Collect sample data in a constant log-time step

NO Collect sample data in a constant time-step

Process the data to simulate constant log-time steps

Store sample data

Make stored data available to a signal processing algorithm

End

Fig. 20
Start

Receive sample data (output)

Receive system characterization (z-transform)

Deconvolute sample data

Z-transform input = z-transform output/z-transform system

Calculate input from z-transform of input

End

Fig. 21
Receive sample data (output)

Apply plurality of noise suppression wavelets to sample data

Generate a set of data peaks

Identify shifting (noise) and stable (data) peaks
Start

2300

Provide a first outer sealing body and a second outer sealing body

2302

Etch a plurality of flow channels into the sealing bodies

2304

Provide a first and second GC column

2306

Provide a valve that switches between a first and second flow regime

2308

Operate the valve in the first flow regime by flowing a sample through a first and second GC column

2310

Operate the valve in the second flow regime by flowing a sample through just the second GC column

2312

Flow an intake air stream through a precon tube in a first direction to concentrate chemicals

2314

Flow the intake air stream in a second direction to deliver a concentrated sample to a GC unit

2316

Heat the precon tube to a specified temperature

2318

Provide a detector circuit, detector circuit seal, and a pressure equalizing channel

2320

End

Fig. 23
1. Field of the Invention

This invention relates to chemical detectors and more particularly relates to gas chromatography sensors.

2. Description of the Related Art

Gas chromatography (GC) is useful in the chemical industry as a separation mechanism and as a sensing mechanism. GC sensors are extremely useful for detecting specific chemicals in a gas with mixed components, but they suffer from the major drawback that they are quite expensive.

The required purities in GC mandate, within most of the current art, the use of valves that cost in the thousands of dollars per valve. One concept has been introduced which allows air pressure to perform some of the gas switching, which allows the expensive valves to be replaced with cheaper solenoid valves, see U.S. Patent No. 4,970,905. However, the present art for accomplishing this requires complicated machining and assembly causing manufacturing expense and reliability problems.

Another limitation of the present art is that manufacture of GC columns is a tedious and expensive process. For example, the GC column must be heated uniformly while in use, and low cost methods to effectively accomplish this uniform heating are lacking in the present art. One current method to provide effective and affordable heating is to co-axially winding a heating element around the GC column—this method is expensive to implement. There are temperature control methods which are easy to manufacture, but which tend to leave the GC column directly exposed to a heating element and thus allow for non-uniform temperature spikes at places along the GC column.

Another limitation of current GC sensor technology is that the sensors need to be periodically calibrated against an internal standard, and no simple methods exist to provide for this. The current technology is to provide a chemical, which must be stored, and an injection mechanism which must inject the chemical into the system without interfering with seals and the normal operation of the GC sensor.

GC sensors typically use a preconcentration mechanism, which multiplies the concentration of chemicals of interest in a sample and allows detection of lower initial concentrations than otherwise allowable. Typically, an adsorption-desorption material is added into the sample stream to accomplish this. Current methods of adding adsorption-desorption materials tend to cause variable pressure drop in the sensor flow paths.

In the current art, the GC sensor must operate at a design operational temperature. Lower temperatures are desirable for better separation of elution times of different components, while higher temperatures improve the sensor response time. However, the test temperature must be at least as high as the ambient temperature. Typically, an operating temperature is selected that is higher than any predicted ambient temperature when the GC sensor is manufactured. This causes the temperature to be set higher than necessary when the actual ambient temperature is low, making chemical detection more difficult than required, and inducing greater energy loss to heat the GC sensor than would otherwise be required.

In GC sensors that detect a wide range of chemicals, the chemicals can have widely variable elution times from the GC column. Further, the shape of the detection peaks for chemicals with different elution times will vary. As a general principle, later eluting chemicals will have a lower and wider peak than early eluting chemicals. Further, in high resolution GC sensors that are detecting concentrations in the parts-per-million (ppm) and parts-per-billion (ppb) ranges, extraneous peaks and noise will occur in the basic signal. This variability in peak shape makes it difficult for detection algorithms to correlate the concentrations of the various chemicals.

A GC sensor will typically have a long GC column placed into a small area, and will typically be wound up as tight as possible. Further, the GC column may be manufactured in one time and location, and transported and/or stored for a period before assembly of the GC sensor. A cheap method to build uniform GC columns, and to protect the columns from the introduction of impurities between the time of manufacture and the time of assembly is desirable.

A dual hyphenated GC sensor, and any GC sensor that is utilized to detect many chemicals simultaneously, or utilized to detect chemicals from a complex mixture of gases, suffers in the current art from difficulty in finding chemical elution peaks within a complex signal. Often a significant amount of noise is produced in the signal. The standard Fourier analysis of GC signals suffer from producing ringing in the signal, especially with high frequency components of the signal. Noise suppression wavelets are known in the art, but any particular noise suppression wavelet will still tend to leave some noise peaks in the signal and complex signals continue to be difficult to interpret.

Proper sealing of GC sensors is a known difficulty in the art, and is especially problematic in sensors attempting to detect chemicals at the low parts-per-million (ppm), or even into the parts-per-billion (ppb) range. The internal flowpaths of the sensor must be protected from leakage to the ambient environment, and the analytical flowpaths containing the chemical sample must be further protected from un-designed fluid migration within the sensor.

From the foregoing discussion, it should be apparent that a need exists for an apparatus, system, and method that detects a broad spectrum of chemicals in a GC sensor in an inexpensive and effective manner. Beneficially, such an apparatus, system, and method would allow the use of inexpensive solenoid valves, provide for easy manufacture, provide for uniform and inexpensive heating of sensing elements, allow for a low cost implementation of an internal chemical standard, provide for manufacture of a preconcentration system that is inexpensive and provides uniform pressure drop, allows low energy operation in a wide range of ambient environments, that robustly detects chemicals that have widely varying elution times, and that is protected from leakage from the ambient environment and internally within the analytical flowpaths.

SUMMARY OF THE INVENTION

Based on the foregoing, Applicant asserts that a need exists for a low cost high resolution chemical detector. The present invention has been developed in response to the present state of the art, and in particular, in response to the problems and needs in the art that have not yet been fully solved by currently...
available gas chromatography (GC) sensor technology. Accordingly, the present invention has been developed to provide an apparatus, system, and method for detecting chemicals present at low concentrations in a GC sensor package that is inexpensive and simple to manufacture.

A GC sensor is disclosed that includes a first outer sealing body and a second outer sealing body. The sensor includes a plurality of flow channels etched into the outer sealing bodies. The sensor includes a first GC column and a second GC column, both columns between the outer sealing bodies. The sensor further includes a valve that switches between a first flow regime and a second flow regime. The first flow regime includes a sample flowing through the first GC column and then the second GC column. The second flow regime includes a sample flowing to the second GC column without flowing to the first GC column. The sensor includes a preconcentration tube, a sampling pump, and a sample switching valve. The preconcentration tube includes a preconcentration material that adsorbs and desorbs chemicals from the sample. The sample switching valve switches between a concentration mode and a sensing mode. The concentration mode includes an intake air stream flowing through the preconcentration tube in a first direction, and the sampling pump sending a dilute sample through a GC unit that includes the first and second GC columns. The sensing mode includes the intake air stream flowing through the preconcentration tube in a second direction, and the sampling pump sending the sample through the GC unit.

An apparatus is disclosed for low cost high resolution chemical detection. The apparatus includes a plurality of flow channels etched into the outer sealing bodies. The apparatus includes a first GC column and a second GC column, both columns between the outer sealing bodies. The apparatus further includes a valve that switches between a first flow regime and a second flow regime. The first flow regime includes a sample flowing through the first GC column and then the second GC column. The second flow regime includes a sample flowing to the second GC column without flowing to the first GC column. The apparatus includes a preconcentration tube, a sampling pump, and a sample switching valve. The preconcentration tube includes a preconcentration material that adsorbs and desorbs chemicals from the sample. The sample switching valve switches between a concentration mode and a sensing mode. The concentration mode includes an intake air stream flowing through the preconcentration tube in a first direction, and the sampling pump sending a dilute sample through a GC unit that includes the first and second GC columns. The sensing mode includes the intake air stream flowing through the preconcentration tube in a second direction, and the sampling pump sending the sample through the GC unit.

In one embodiment, the apparatus includes a first resistance, and a fourth resistance. The first flow regime further includes a first fluid stream from the first pump that flows through the first GC column and the second GC column, and a second fluid stream directed by the valve that flows through the fourth resistance and the first resistance. The second flow regime further includes a third fluid stream from the first pump that flows through the first GC column and the first resistance, and a fourth fluid stream directed by the valve that flows through the fourth resistance and the second GC column, wherein the fourth fluid stream further prevents the third fluid stream from flowing through the second GC column.

In one embodiment, the apparatus includes a first pump, a second pump, and a first resistance. The first flow regime further includes a first fluid stream from the first pump that flows through the first GC column and the second GC column, and a second fluid stream directed by the valve that flows through the fourth resistance and the first resistance. The second flow regime further includes a third fluid stream from the first pump that flows through the first GC column and the first resistance, and a fourth fluid stream directed by the valve that flows through the fourth resistance and the second GC column, wherein the fourth fluid stream further prevents the third fluid stream from flowing through the second GC column.

In one embodiment, the apparatus includes a first pump, a second pump, and a first resistance. The first flow regime further includes a first fluid stream from the first pump that flows through the first GC column and the second GC column, and a second fluid stream directed by the valve that flows through the first pump. The second flow regime further includes a third fluid stream from the first pump that flows through the first GC column and the first resistance, and a fourth fluid stream directed by the valve that flows through the fourth resistance and the second GC column, wherein the fourth fluid stream further prevents the third fluid stream from flowing through the second GC column.

In one embodiment, the apparatus includes a first pump, a second pump, and a first resistance. The first flow regime further includes a first fluid stream from the first pump that flows through the first GC column and the second GC column, and a second fluid stream directed by the valve that flows through the fourth resistance and the first resistance. The second flow regime further includes a third fluid stream from the first pump that flows through the first GC column and the first resistance, and a fourth fluid stream directed by the valve that flows through the fourth resistance and the second GC column, wherein the fourth fluid stream further prevents the third fluid stream from flowing through the second GC column.

In one embodiment, the apparatus includes a detection circuit that detects a target chemical eluting from the first and second GC columns, wherein the target chemical occurs in an ambient environment at less than about 1,000 parts-per-billion. The apparatus further includes a preconcentration tube, a sampling pump, and a sample switching valve that switches between a concentration mode and a sensing mode. The preconcentration tube includes a preconcentration material that adsorbs and desorbs chemicals from an intake air stream. The concentration mode includes flowing the intake air stream through the preconcentration tube in a first direction, and the sampling pump providing a dilute sample to a GC unit comprising the first and second GC columns. The sensing mode includes flowing the intake air stream through the preconcentration tube in a second direction, and the sampling pump providing a concentrated sample to the GC unit.

The apparatus includes a detector circuit in one embodiment. The detector circuit is between the outer sealing bodies, and includes a detector circuit seal. The apparatus includes, in one embodiment, an independent spring to apply sealing force to enhance the detector circuit seal. The apparatus includes a pressure equalizing channel configured to equalize pressures between the detector circuit and a sample channel. A method is disclosed for low cost high resolution chemical detection. The method includes providing a first outer sealing body and a second outer sealing body, etching a plurality of flow channels into the first sealing body and the second sealing body, and providing a gas chromatography (GC) column and a second GC column interposed between the first and second outer sealing bodies. The method further includes providing a valve that switches between a first flow regime and a second flow regime. Operating the valve in the first flow regime includes flowing a sample through the first GC column and the second GC column. Operating the valve in the second flow regime includes flowing the sample through the second GC column without flowing the sample through the first GC column.

In one embodiment, the method includes flowing an intake air stream through a preconcentration tube in a first direction
to concentrate chemicals on the preconcentration tube, and flowing the intake air stream through the preconcentration tube in a second direction to deliver a concentrated sample through a GC unit comprising the first and second GC columns. In one embodiment, the method further includes heating the preconcentration tube to a specified temperature, thereby releasing a known chemical from the preconcentration tube, and detecting elution of the known chemical from the GC unit. The method may include providing a detector circuit interposed between the first and second outer sealing bodies, and providing a detector circuit seal. In one embodiment, the method includes providing a pressure equalizing channel from a sample channel to the detector circuit.

Reference throughout this specification to features, advantages, or similar language does not imply that all of the features and advantages that may be realized with the present invention should be or are in any single embodiment of the invention. Rather, language referring to the features and advantages is understood to mean that a specific feature, advantage, or characteristic described in connection with an embodiment is included in at least one embodiment of the present invention. Thus, discussion of the features and advantages, and similar language, throughout this specification may, but do not necessarily, refer to the same embodiment.

Furthermore, the described features, advantages, and characteristics of the invention may be combined in any suitable manner in one or more embodiments. One skilled in the relevant art will recognize that the invention may be practiced without one or more of the specific features or advantages of a particular embodiment. In other instances, additional features and advantages may be recognized in certain embodiments that may not be present in all embodiments of the invention.

These features and advantages of the present invention will become more fully apparent from the following description and appended claims, or may be learned by the practice of the invention as set forth hereinafter.

BRIEF DESCRIPTION OF THE DRAWINGS

In order that the advantages of the invention will be readily understood, a more particular description of the invention briefly described above will be rendered by reference to specific embodiments that are illustrated in the appended drawings. Understanding that these drawings depict only typical embodiments of the invention and are not therefore to be considered to be limiting of its scope, the invention will be described and explained with additional specificity and detail through the use of the accompanying drawings, in which:

FIG. 1 is a schematic block diagram illustrating one embodiment of a system to detect a broad spectrum of chemicals in accordance with the present invention;

FIG. 2A is a schematic block diagram illustrating one embodiment of a controller for a GC sensor in accordance with the present invention;

FIG. 2B is a schematic block diagram illustrating one embodiment of a controller for a GC sensor in accordance with the present invention;

FIG. 3 is a schematic block diagram illustrating one embodiment of an apparatus to control a GC sensor in accordance with the present invention;

FIG. 4 is a schematic block diagram illustrating one embodiment of an apparatus to control flows to GC columns within a GC sensor in accordance with the present invention;

FIG. 5 is a schematic block diagram illustrating one embodiment of an apparatus to control flows to GC columns within a GC sensor in accordance with the present invention;

FIG. 6 is a schematic block diagram illustrating an alternative embodiment of an apparatus to control flows to GC columns within a GC sensor in accordance with the present invention;

FIG. 7 is a schematic block diagram illustrating an alternative embodiment of an apparatus to control flows to GC columns within a GC sensor in accordance with the present invention;

FIG. 8 is a schematic block diagram illustrating one embodiment of an apparatus to control sampling flows within a GC sensor in accordance with the present invention;

FIG. 9 is a schematic block diagram illustrating one embodiment of an engineered pressure balancing leak in accordance with the present invention;

FIG. 10 is a schematic block diagram illustrating one embodiment of an apparatus to seal a GC sensor and detector circuit in accordance with the present invention;

FIG. 11 is a schematic block diagram illustrating one embodiment of an apparatus to uniformly heat a GC column in accordance with the present invention;

FIG. 12A is a schematic block diagram illustrating one embodiment of a slot for packing a preconcentration material in accordance with the present invention;

FIG. 12B is a schematic block diagram illustrating one embodiment of a packed preconcentration material in accordance with the present invention;

FIG. 12C is a schematic block diagram illustrating an alternative embodiment of a packed preconcentration material in accordance with the present invention;

FIG. 13 is an illustration of sampling data in accordance with the present invention;

FIG. 14 is an illustration of alternative sampling data in accordance with the present invention;

FIG. 15 is an illustration of sampling data adjusted with a plurality of noise wavelets in accordance with the present invention;

FIG. 16 is a schematic flow diagram illustrating one embodiment of a method to manufacture a GC column in accordance with the present invention;

FIG. 17 is a schematic flow diagram illustrating one embodiment of a method to utilize an internal standard chemical in a GC sensor in accordance with the present invention;

FIG. 18 is a schematic flow diagram illustrating one embodiment of a method to pack a preconcentration material in accordance with the present invention;

FIG. 19 is a schematic flow diagram illustrating one embodiment of a method to control the temperature of a GC column in accordance with the present invention;

FIG. 20 is a schematic flow diagram illustrating one embodiment of a similarity sequencing sample data acquisition method in accordance with the present invention;

FIG. 21 is a schematic flow diagram illustrating one embodiment of a method for analyzing sampling data in accordance with the present invention;

FIG. 22 is a schematic flow diagram illustrating one embodiment of a method for identifying data peaks and noise peaks in a set of sampling data in accordance with the present invention; and

FIG. 23 is a schematic flow diagram illustrating one embodiment of a method for low cost high resolution chemical detection in accordance with the present invention.

DETAILED DESCRIPTION OF THE INVENTION

It will be readily understood that the components of the present invention, as generally described and illustrated in the
figures herein, may be arranged and designed in a wide variety of different configurations. Thus, the following more detailed description of the embodiments of the apparatus, system, and method of the present invention, as presented in FIGS. 1 through 23, is not intended to limit the scope of the invention, as claimed, but is merely representative of selected embodiments of the invention.

Many of the functional units described in this specification have been labeled as modules, in order to more particularly emphasize their implementation independence. For example, a module may be implemented as a hardware circuit comprising custom VLSI circuits or gate arrays, off-the-shelf semiconductors such as logic chips, transistors, or other discrete components. A module may also be implemented in programmable hardware devices such as field programmable gate arrays, programmable array logic, programmable logic devices or the like.

Modules may also be implemented in software for execution by various types of processors. An identified module of executable code may, for instance, comprise one or more physical or logical blocks of computer instructions which may, for instance, be organized as an object, procedure, or function. Nevertheless, the executables of an identified module need not be physically located together, but may comprise disparate instructions stored in different locations which, when joined logically together, comprise the module and achieve the stated purpose for the module.

Indeed, a module of executable code may be a single instruction, or many instructions, and may even be distributed over several different code segments, among different programs, and across several memory devices. Similarly, operational data may be identified and illustrated herein within modules, and may be embodied in any suitable form and organized within any suitable type of data structure. The operational data may be collected as a single data set, or may be distributed over different locations including over different storage devices, and may exist, at least partially, merely as electronic signals on a system or network.

Reference throughout this specification to “one embodiment” or “an embodiment” means that a particular feature, structure, or characteristic described in connection with the embodiment is included in at least one embodiment of the present invention. Thus, appearances of the phrases “in one embodiment” or “in an embodiment” in various places throughout this specification are not necessarily all referring to the same embodiment.

Furthermore, the described features, structures, or characteristics may be combined in any suitable manner in one or more embodiments. In the following description, numerous specific details are provided, such as examples of materials, fasteners, sizes, lengths, widths, shapes, etc., to provide a thorough understanding of embodiments of the invention. One skilled in the relevant art will recognize, however, that the invention can be practiced without one or more of the specific details, or with other methods, components, materials, etc. In other instances, well-known structures, materials, or operations are not shown or described in detail to avoid obscuring aspects of the invention.

FIG. 1 is a schematic block diagram illustrating one embodiment of a system 100 to detect a broad spectrum of chemicals in accordance with the present invention. The system 100 may comprise a gas chromatography (GC) sensor, and a controller 104. The controller may comprise at least one module configured to control one or more aspects of the GC sensor. The modules in one embodiment may comprise a temperature control module 106, a GC column switching module 108, a sample introduction module 110, a similarity sequencing module 112, a signal processing module 114, and a noise-filtering module 116.

The temperature control module 106 may be configured to control the temperature of one or more GC columns within the GC sensor. The temperature control module may be configured to control the temperature of the GC column(s) based on the current ambient temperature and a set of chemical elution data corresponding to a set of temperatures.

The GC column switching module 108 may be configured to control gas flows through at least one GC column in the GC sensor 102. The GC column switching module 108 may be configured to control the flows such that a gas flow passes through a first GC column into a second GC column in series. The GC column switching module 108 may be further configured to control the flows such that a first and second GC column each receive a gas flow in parallel. The GC column switching module 108 may be further configured to ensure that a first and second GC column receive substantially the same flow rate of gas.

The sample introduction module 110 may be configured to introduce a sample gas into at least one GC column. The sample introduction module 110 may be configured to control a sample flow in a concentration flow regime configured to concentrate a sample gas onto a preconcentration material, which may be configured to adsorb the sampled chemicals of interest. The sample introduction module 110 may be further configured to control a sample flow in a desorption flow regime to desorb a sample gas from the preconcentration material, and to flow the concentrated sample through at least one GC column.

The similarity sequencing module 112 may be configured to take data samples in a constant log-time fashion to ensure that early eluting and late eluting chemicals exhibit qualitatively similar data peaks. The similarity sequencing module 112 may be configured in one embodiment to take data samples in a constant time fashion, and to process the data to simulate a constant log-time data set.

The signal processing module 114 may be configured to deconvolute a sampling data set to determine the chemical inputs to the at least one GC column that generate the eluted chemicals observed in the sampling data. The signal processing module 114 may be configured to deconvolute the sampling data utilizing a Z-transform. The signal processing module 114 may be configured to convert the sequential sampling data into a high order polynomial, divide the high order polynomial by a polynomial system model, and thereby generate an input polynomial. The signal processing module 114 may be further configured to regenerate the predicted input signal by an inverse Z-transform of the input polynomial. The Z-transform may be modified to use the largest polynomial divisor possible without generating negative values. The modified Z-transform may be enabled by the near constant width in sample space of the chemical elution peaks generated by the similarity sequencing module 112.

The noise filtering module 116 may be configured to operate a noise suppression wavelet and/or other noise suppression method on the sampling data to suppress noise peaks. The noise filtering module 116 may be further configured to operate a plurality of noise suppression wavelets on the sampling data, and to identify one or more peaks as noise, and one or more peaks as data. The noise filtering module 116 may be further configured to identify relatively stable peaks as data, and relatively unstable peaks as noise.

FIG. 2A is a schematic block diagram illustrating one embodiment of a controller 104 for a GC sensor 102 in accor-
dance with the present invention. The controller 104 may comprise a plurality of modules to functionally execute the controller 104 operations.

The controller 104 may comprise a temperature control module 106 configured to maintain a GC target temperature 206 at a lowest feasible temperature to maintain elution time separation of closely related chemicals and to minimize the heating burden on the GC sensor 102. The temperature control module 106 may be configured to determine an ambient temperature 202. The temperature control module 106 may be further configured to read a stored set of temperature-based elution data 204. The temperature control module 106 may then select a GC target temperature 206 based on the ambient temperature 202 and the set of temperature-based elution data 204.

In one embodiment, the temperature control module 106 may be configured to select the next available temperature from the set of temperature-based elution data 204 higher than the ambient temperature 202. In one example, the set of temperature-based elution data 204 comprises elution data 204 at 50°F, 100°F, and 150°F. In the example, the temperature control module 106 may select a GC target temperature of 100°F when the ambient temperature 202 is 65°F.

In one embodiment, the temperature control module 106 may be configured to interpolate elution data between available temperatures in the set of temperature-based elution data 204, and may be configured to select a GC target temperature 206 at any desired temperature. For example, the set of temperature-based elution data 204 may comprise elution data 204 at 50°F, 100°F, and 150°F, and the temperature-based elution data 204 may be configured to select a GC target temperature 10°F higher than the ambient temperature 202, or 75°F when the ambient temperature 202 is 65°F. The interpolation may be simple interpolation, or where greater accuracy is required the interpolation could occur through the application of fundamental mass diffusion equations.

The temperature control module 106 may be further configured to provide a heating element command 208, which may be a physical control of a heating element, a datalink command to another portion of the controller 104 to control the heating element, or the like. The heating element may be controlled through a standard control scheme such as a proportional-integral-derivative (PID) controller to control the GC column(s) to the GC target temperature 206.

In one embodiment, the set of temperature-based elution data 204 contains one set of data for a first GC column, and a second set of data for a second GC column. The GC target temperature 206 may comprise a target temperature 206 for each GC column, and the target temperatures 206 may be different values for each GC column.

The controller 104 may comprise a GC column switching module 108 configured to control gas flows through at least one GC column in the GC sensor 102. The GC column switching module 108 may be configured to control the flows in a first flow regime 210 such that a gas flow passes through a first GC column into a second GC column in series. The GC column switching module 108 may be further configured to control the flows in a second flow regime 210 such that a first and second GC column each receive a gas flow in parallel. The GC column switching module 108 may be further configured to ensure that a first and second GC column receive substantially the same flow rate of gas.

The GC column switching module 108 may comprise commands to one or more valves and one or more pumps to achieve the flow regime switches. The commands may comprise physical control of the valves and/or pumps, a datalink command to another portion of the controller 104, or the like.

The controller 104 may comprise a sample introduction module 110 configured to introduce a sample gas into at least one GC column. The sample introduction module 110 may be configured to control a sample flow in a concentration flow regime 212 configured to concentrate a sample gas onto a preconcentration material, which may be configured to absorb the sampled chemicals of interest. The sample introduction module 110 may be further configured to control a sample flow in a desorption flow regime 212 to desorb a sample gas from the preconcentration material, and to flow the concentrated sample through the at least one GC column.

The sample introduction module 110 may comprise commands to one or more valves and one or more pumps to achieve the flow regime switches. The commands may comprise physical control of the valves and/or pumps, a datalink command to another portion of the controller 104, or the like.

The controller 104 may comprise a similarity sequencing module 112 configured to take data samples in a constant log-time fashion. Early eluting chemicals tend to have a sharper peak shape and to elute in a short period of time. Later eluting chemicals tend to have a flatter peak shape and to elute over a longer period of time. Therefore, the later eluting chemicals tend to have a peak created from a much larger number of samples than earlier eluting peaks, and the different shapes of the peaks tend to make algorithms less likely to detect them. Taking data in a constant log-time fashion tends to clean up the peaks and make early and late eluting chemicals show similar looking peaks. In one example, the similarity sequencing module 112 may be configured to take data samples 214 at each 0.2 log seconds, or the normal time value of data point value “n” equals eⁿ. In the example, data point 12 would be (12e0.2=12.2) log-time 2.4, and the normal time value would be 11.02 seconds. Logarithm values other than base “e”, or the natural logarithm, are possible, as the natural logarithm is used only for illustration.

Many applications have a natural data sampling frequency due to controller 104 execution times and physical limitations of the sensor 102. Therefore, the similarity sequencing module 112 may be configured in one embodiment to take data samples 214 in a constant time fashion, and to process the data to simulate a constant log-time data set 216. For example, the similarity sequencing module 112 may be configured to physically collect data each 0.2 seconds. To simulate the 15⁰ log-time data point, the time data from (“e”(15°0.2)=) 20.08 seconds to (“e”(16°0.2)=) 24.53 seconds would be used. Therefore, the constant time data points 214, 216, as well as part of data point 100, and part of data point 123, would be integrated to simulate the 15° log-time data point 216.

A rectangulär approximation or other integrating algorithm could be used to integrate the data between the given sample points 214. Simpson’s rule, trapezoidal, and polynomial approximations can be used as well, although these integrating algorithms provide little benefit of improved accuracy over a rectangular approximation where the constant time data interval is small, and those algorithms, for example Simpson’s rule, may amplify high frequency signal noise.

The signal processing module 114 may be configured to deconvolute a sampling data set 216 to clarify data peaks and find eluted chemicals in the sampling data. The sampled data set 216 may be affected in time, or convoluted, due to diffusion and separation in the at least one GC tube. The deconvolution process may recover the original signal, which is typically a chemical concentration in GC sensors 102. The signal processing module 114 may be configured to deconvolute the data set 216 with the largest polynomial division
that does not produce an unstable data response. The signal processing module 114 may be further configured to utilize a Z-transform in sampling point space to determine the input signal according to the following equation where the Z-transform of the system 218 may be a transfer function describing the characteristics of the system:

\[
\frac{Z_{\text{output}}}{Z_{\text{system}}} = Z_{\text{input}}.
\]

Therefore, the inverse transform of the result of Equation 1 provides the input data 220 or the information from the sampling data input. A Fourier transform can also be used in deriving the data, although the Fourier transform is more susceptible to ringing from high frequency noise.

The signal processing module 114 may be configured to deconvolve the sampling data set to clarify data peaks and find eluted chemicals in the sampling data by converting the sampling data set 216 into a high order polynomial, for example by a regression fit. The signal processing module 114 may be further configured to interpret a model 218 of the GC column system, which may be a transform function in the form \( N_d / D_s \), or a rational polynomial function. In some embodiments, either \( N_d \) or \( D_s \) may be 1, reducing the transform function to \( 1 / D_s \) or \( N_d \), respectively. Those of skill in the art will recognize that if the roots of \( D_s \) fall within the unit circle, the signal convolution is stable.

The signal processing module 114 may be configured to label the input chemical sample function as \( U_s \), the output function as \( Y_s \), and the system model as \( G \), and to label the Z-transforms of those functions as \( U_z, Y_z, \) and \( G_z \). The input function may be convoluted by the GC columns such that \( Y_z = G_z * U_z, \) where \( Y_z \) is the measured output at the detector, and \( U_z \) is the Z-transformed desired input information. Therefore, it is apparent that equation 2 yields the desired input information.

\[
Z^{-1}(U_z) = Z^{-1}(Y_z/G_z) = Z^{-1}((Y_z*G_z)/N_z)
\]

Equation 2.

The signal processing module 114 may be configured to modify the Z-transform division to ensure it is stable. This may be accomplished with a standard division configured to avoid a negative result. In the following example, polynomials are expressed as coefficients only without the related powers (e.g. \( X^4 + 2X^3 + 3 \)). In one example, \( N_z \) may be \([3 1 2 1 2 3 2] \) while \( D_z \) may be \([1 2 1] \). The first factor to check may be \( 1/3 \), generating a first intermediate result of \( [2 3 1 3 1 2 3 1] \), or \( [0 0 1 2 1 3 2] \) with the result being (1). Note that the result contains negative values, and is therefore unstable. The second intermediate result is \( [0 0 1 2 3 2 1] \) with the result being (1). The next becomes \( [0 0 0 1 2 1] \) result (1 - 1 - 4). The result is beginning to exhibit fluctuations.

Continuing the analysis by testing factors under the restriction of no negative results, it is apparent that the first factor for the example should be 1. With 1 the result will be \( [2 1 0 2 3 2 1] \). As there are no negative values this is acceptable. Proceeding to the next factor, 1 is selected. This also produces negative values so it is reduced to 0. The second result would be \( [2 1 0 2 3 2 1] \) with the result being (10). The third is \( [2 1 0 2 3 2 1] \) with the result (100). The fourth is \( [2 1 0 0 0 1 0 1] \) and (1002). Continuing to the end yields \( [2 1 0 0 0 1 0 1] \) and (1002000).

The signal processing module 114 may be configured to complete the deconvolution under equation 2. The modified Z-transform takes care of any instability introduced by any problematic zeros. Note that the modified z transform method makes an implicit assumption that all features of interest convolute similarly as the divisor is constant. If the divisor is not constant, for example because the width of peaks of interest increases at later elute times then further modification may be utilized. A first modification is to change the divisor for each time period of interest. This is within the skill of one in the art, but may not be the preferable solution in some circumstances. A second modification is to adjust the time sampling such that the peaks have similar features and the constant divisor remains valid. The similarity sequencing module 112 may be configured to perform the second modification. In embodiments utilizing a Fourier transform or other deconvolution methods, the divisor issue remains and the modifications listed may still be utilized in some embodiments.

The noise filtering module 116 may be configured to operate a plurality of noise suppression wavelets 222 and/or other noise suppression methods on the sampling data, and to identify one or more peaks as noise, and one or more peaks as data. Each noise suppression methodology may make assumptions about the noise shape. These assumptions are known as the noise model. Changing the noise model will affect the result of the noise suppression step, which will introduce or eliminate different noise generated artifacts in the results.

The noise filtering module 116 may be further configured to identify relatively stable peaks as data, and relatively unstable peaks as noise. A stable peak in this context is a peak that is present even when several noise suppression methods are used. An unstable peak is one whose presence is dependent on the noise model used and thus is not present in some of the responses. The noise filtering module 116 may be configured to operate a noise suppression wavelet 222 or other noise suppression method on the sampling data to suppress noise peaks. The noise filtering module 116 may be further configured to operate a plurality of noise suppression wavelets 222 on the sampling data, and to identify one or more peaks as noise 224, and one or more peaks as data 224. The noise filtering module 116 may be configured to identify relatively stable peaks as data, and relatively unstable peaks as noise.

In one embodiment, the noise filtering module 116 may be configured to operate a set number of noise filtering wavelets 222 on the sampling data at each time step, and to identify peaks 224 which remain substantially constant as data, and peaks 224 which move or intermittently appear as noise. Substantially constant may comprise a range of amplitudes and a range of time values wherein a peak can appear and still be considered to be the same peak. Moving or intermittently appearing may comprise values outside of the range of amplitudes and the range of time values wherein a peak can appear and still be considered to be the same peak.

In one embodiment, the noise filtering module 116 may be configured with a larger number of noise suppression wavelets 222 than the noise filtering module 116 may run on each execution time step. In one example, the noise filtering module 116 may comprise ten noise suppression wavelets 222, and the noise filtering module 116 may operate three noise suppression wavelets 222 at each time step. The three noise suppression wavelets may comprise a random selection from the ten available wavelets 222, a rotation within the ten available wavelets 222, or a primary noise suppression wavelet 222 and two wavelets selected from the other nine available wavelets 222. This embodiment avoids having a noise suppression wavelet 222 that may be sensitive in some operating conditions dominate the signal, while improving the operational performance of the controller 104 compared to running all wavelets 222 at every execution cycle.
FIG. 2B is a schematic block diagram illustrating one embodiment of a controller 104 for a GC sensor 102 in accordance with the present invention. In the embodiment of FIG. 2B, the apparatus includes a preconcentration tube (refer to the sections referencing FIGS. 4 through 8B) having a preconcentration material that adsorbs and desorbs chemicals from an intake air stream. The preconcentration material, in one embodiment, releases a known chemical at a specified temperature 226. The GC sensor 102 includes an internal standard delivery module 228 that heats the preconcentration material to the specified temperature 226.

The internal standard delivery module 228 may heat the preconcentration material by issuing a heat preconcentration command 230 to an actuator such as a resistive heater, and/or similar method known in the art. The internal standard delivery module 228 may be configured to heat the preconcentration material at a maintenance schedule, upon a request, upon the detection of a GC sensor fault 102, and the like. Upon heating to the specified temperature 226, the preconcentration material creates a known chemical release 232, which a calibration module 234 is configured to detect. The calibration module 234 detects elution of the known chemical from a GC unit comprising a first and second GC column (refer to the description referencing FIGS. 8A and 8B, for example), and provides known chemical elution data 236. The system 100 may be configured to utilize the known chemical elution data 236 to provide dynamic information about the system (e.g. a system transfer function), to determine a sensor 102 fault condition, and the like.

FIG. 3 is a schematic block diagram illustrating one embodiment of an apparatus 300 to seal a GC sensor 102 and detector circuit 316 in accordance with the present invention. The apparatus 300 may comprise a first sealing surface 304 configured to seal the sensor 102 from an ambient environment. The first sealing surface 304 may be an epoxy or similar sealant configured to seal the material of the sensor 102 body which may comprise a machineable ceramic. In one embodiment, an acrylic GP sealant is used at the sealing surface 304. The apparatus 300 may further comprise a second sealing surface 306 configured to seal a detector circuit 316 from internal leaks within the sensor 102.

The first sealing surface 304 may seal the faces of a first outer sealing body and a second outer sealing body, wherein the outer sealing bodies together comprise the body of the sensor 102. Refer to the description referencing FIG. 10.

The apparatus may further comprise a GC unit 308 which may comprise at least one GC column, and a sample unit 310 configured to provide the sample gas to the sensor 102 and GC unit 308. The sample may pass from the GC unit 308 to the detector 316. The detector 316 may comprise any detection device used in the GC art—including a thermal conductivity detector (TCD), a mass spectrometer, flame ionization detector, photo-ionization detector, electron capture detector, Hall electrolytic conductivity detector, and the like. In one embodiment, the detector 316 comprises a TCD, and the detector 316 is configured to generate an electrical signal based on the detected thermal conductivity of the sample gas on one side of a Wheatstone bridge, with an electrical signal based on the detected thermal conductivity of a reference gas on the other side of the Wheatstone bridge. This known compensation technique removes common mode noise, or background noise, from the signal and focuses the detection on the sample 310 gas.

The apparatus 300 may comprise a controller 104, which may communicate with the detector 316, an ambient temperature sensor 312, and a GC unit temperature sensor 314. The temperature control module 106 may be configured to utilize the temperature sensors 312, 314 to control the temperature of the GC column(s) within the GC unit 308.

Regarding FIGS. 4 through 8B, embodiments with two different switching schemes are described. The first switching scheme is designed to implement the switching between two GC columns GC1, GC2, and embodiments of this scheme are described in FIGS. 4 through 7. The second switching scheme is used to load and unload sampled chemicals on a preconcentration tube 402, and to alternate sample air and clean air to the inlet of GC1. One embodiment of the second switching scheme is detailed in FIGS. 8A and 8B. A given embodiment of the invention may comprise either or both switching schemes. They are illustrated separately to clarify the features of the invention, and it is a mechanical step for one of skill in the art to combine embodiments of the first and second switching schemes in a given embodiment of the invention.

FIG. 4 is a schematic block diagram illustrating one embodiment of an apparatus 400 to control flows to GC columns within a GC sensor 102 in accordance with the present invention. FIGS. 4 through 8B use the standard convention that where a flow depends upon the position of a valve, a dashed line indicates that the given flow is not occurring with the valve in the position as shown within that Figure. The apparatus 400 may comprise a first GC column GC1, a second GC column GC2, and a plurality of flow resistances (restrictions) R1, R2, R3. The first and second GC columns GC1, GC2 are interposed between the first and second outer sealing bodies. The GC columns may be disposed within a cavity machined or cast into the sealing bodies.

The flow resistances R1, R2, R3 may comprise orifices, controllable valves, inserted microbore with porous substrate, or any other type of configurable pressure drop available in the art. In one embodiment, the flow resistances comprise flow channels sized to achieve a specified pressure drop at a specified flow rate. The flow channels of the apparatus 400 may be etched on the surfaces of opposing faces of the sensor 102 body, or they may be machined flow paths within a sensor 102 body.

The apparatus 400 may comprise a preconcentration tube 402, a pump 404, and a molecular sieve 406. The molecular sieve 406 may be configured to remove water and/or other impurities from the gas flow in the apparatus 400, and may be affixed between the pump 404 inlet and outlet. The apparatus 400 shows only the relative flows of GC1 and GC2, while other flows into and out of the apparatus 400 are not shown to avoid cluttering the essential aspects of the embodiment of the invention. Significantly, the introduction of sample 310 gas into the system is not shown. Sample 310 gas may be introduced at the pump 404 through the molecular sieve, for example.

The apparatus may further comprise a valve 408 configured to direct flow through resistance R2 or resistance R3. The valve 408 may comprise a solenoid valve. In FIG. 4, the valve 408 is directing flow through resistance R2. The flow through R2 carries the flow out of GC1 into GC2, thereby connecting the GC columns in series, and sending the output of GC1 and GC2 into the detector 316. The detector 316 effluent may vent to the atmosphere 410. In one embodiment, a majority of the flow through R2 may flow through R1 and recycle through the pump 404.

FIG. 4 illustrates the valve 408 set to the first flow regime. In the embodiment of FIG. 4, a first fluid stream 412 from the pump 408 flows through the first GC column GC1 and the second GC column GC2. A second fluid stream 414 directed by the valve 408 flows through the second resistance R2 and the first resistance R1.
The depiction in FIG. 4 thereby describes a valve 408 that switches between a first flow regime (as depicted in FIG. 4) and a second flow regime (as depicted in FIG. 5). The flow channels depicted in FIGS. 4 through 8B are etched into the first sealing body and the second sealing body such that when the sealing bodies are placed together, sealed flow channels are thereby created. The first flow regime comprises a sample (starting at the pump 404) flowing through the first GC column GC1 and then the second GC column GC2. The second flow regime (refer to FIG. 5) comprises a sample (starting at the pump 404) flowing through the second GC column GC2 without flowing through the first GC column GC1.

Referring to FIG. 5, the valve 408 is directing flow through restriction R3. The flow through R3 forces the flow from GC1 away from GC2, and through R1 for venting or recycling. The flow through GC2 is provided by the pump 404. It is apparent from FIGS. 4 and 5 that the apparatus 400 is configured to direct gas flows through the GC columns GC1, GC2 in series or parallel with the use of a solenoid valve 408.

FIG. 5 illustrates the valve 408 set to the second flow regime in the embodiment of FIG. 5, a third fluid stream 502 from the pump 408 flows through the first GC column GC1 and the first resistance R1. A fourth fluid stream 504 directed by the valve flows through the third resistance R3 and the second GC column GC2. The fourth fluid stream 504 further prevents the third fluid stream 502 from flowing through the second GC column GC2.

FIG. 6 is a schematic block diagram illustrating an alternative embodiment of an apparatus 600 to control flows to GC columns GC1, GC2 within a GC sensor 102 in accordance with the present invention. Referring to FIGS. 4 and 5, it is apparent that for the flow rates through GC1 and GC2 to be identical in either position of the valve 408, a condition which may be desirable for the detector 316, the flow restrictions R2, R3 must be identical. Referring back to FIG. 6, those flow restrictions may be replaced with a single restriction R4 before the valve 408 which enforces this condition more effectively. The embodiment of FIG. 6 is otherwise identical to the embodiment of FIG. 5.

The embodiment of FIG. 6 thus depicts a first flow regime comprising a first fluid stream from the pump 408 that flows through the first GC column GC1 and the second GC column GC2, and a second fluid stream directed by the valve 408 that flows through the fourth resistance R4 and the first resistance R1. The valve 408 in FIG. 6 is depicted in the position to induce the first flow regime. FIG. 6 further depicts a second flow regime comprising a third fluid stream from the pump 408 that flows through the first GC column GC1 and the first resistance R1, and a fourth fluid stream directed by the valve 408 that flows through the fourth resistance R4 and the second GC column GC2. The fourth fluid stream further prevents the third fluid stream from flowing through the second GC column GC2. The valve 408 would be turned—similar to the embodiment depicted in FIG. 5—to induce the second flow regime.

FIG. 7 is a schematic block diagram illustrating an alternative embodiment of an apparatus 700 to control flows to GC columns GC1, GC2 within a GC sensor 102 in accordance with the present invention. Referring to FIG. 6, it is apparent that for the flow rates through GC1 and GC2 to be identical in either position of the valve 408, the flow restriction R4 must dominate the observed pressure drops for flow throughout the apparatus 600. Referring back to FIG. 7, the single pump 404 is replaced with two pumps 702, 706 which may comprise corresponding molecular sieves 704, 708.

The two pumps 702, 706 may enforce the flow rates through GC1 and GC2 to be identical because the pump 607 controls the flow rate through GC1, and the pump 702 can control the flow rate through GC2. The controller 104 may be configured to control the pumps 702, 704. The restriction R4 may be removed in the apparatus 700, although it may be included (not shown), or lumped with R1 to place the restriction on the low pressure side of the pump 702 instead of the high pressure side if desired. The removal of the restriction R4 may cause a lower nominal pressure in the analysis flow paths of the sensor 102, and thereby increase the sensitivity of the GC sensor 102 to leaks. It is within the skill of one in the art to weigh the increased manufacturing costs to manage leaks, a higher pressure load on the pump 702, and a loss in sensor 102 measurement capability due to unmanaged leaks when determining the inclusion of the restriction R4.

Thus, FIG. 7 depicts an embodiment comprising a first pump 706 and a second pump 702. In the embodiment of FIG. 7, a first flow regime comprises a first fluid stream from the pump 702 that flows through the first GC column GC1 and the second GC column GC2. The first flow regime further includes a second fluid stream directed by the valve 408 from the second pump 702 that flows through the first resistance R1. The second stream further prevents the first stream from flowing through the first resistance R1. The valve 408 in FIG. 7 is positioned to induce the first flow regime.

FIG. 7 further depicts a second flow regime comprising a third fluid stream from the first pump 706 that flows through the first GC column GC1 and the first resistance R1, and a fourth fluid stream directed by the valve 408 from the second pump 702 that flows through the second GC column GC2. The fourth stream further prevents the third stream from flowing through the second GC column GC2. The valve 408 would be turned—similar to the embodiment of FIG. 5—to induce the second flow regime. In the embodiment of FIG. 7, sample may be introduced at the first pump 706.

FIG. 8A is a schematic block diagram illustrating one embodiment of an apparatus 800 to control sampling flows within a GC sensor 102 in accordance with the present invention. The flow channels of the apparatus 800 may be etched on the surfaces of opposing faces of the sensor 102 body, or they may be machined flow paths within a sensor 102 body. In one embodiment, the flow channels may comprise ceramic or quartz inserts in the analytical (i.e. sample-containing) portions of the sensor 102 to further enhance sealing of the sensor 102 and allow lower concentrations of chemicals in the sample 310 to be detected. Such inserts are estimated to allow detections down into the parts-per-billion (ppb) range—for example below about 1,000 ppb. The apparatus 800 may comprise a valve 804 configured to operate the apparatus 800 in the concentration or desorption modes. The apparatus 800 of FIG. 8 is shown in the concentration mode. Some of the valves and flow paths similar to those depicted in FIGS. 4 through 7 are removed from FIG. 8 to avoid obscuring aspects of the present invention. However, in one embodiment, FIG. 8 retains the pump(s) 404, 702, 706, and valve 404 to allow flow through the GC columns GC1, GC2 in series and/or parallel as shown in FIGS. 4 through 7.

In the embodiment of FIG. 8A, the sample 310 is introduced to the preconcentration tube 402 which may adsorb the chemicals of interest. A pump 806 may send gas through a carrier gas flow restriction R6 and to the GC unit 308. Some of the pump 806 effluent may recycle through a desorption flow restriction R7 and return to the pump 806 through the valve 804. The flow may pass from the GC unit 308 to the detector 316, where it may flow through a system flow restriction R5 and to an atmospheric vent 808 or back to the pump 806. Therefore, in one embodiment of the concentration
mode, the preconcentration tube 402 is concentrating the sample gas, and the GC unit 308 is receiving clean ambient or carrier gas.

In one embodiment, FIG. 8A depicts a preconcentration tube 402, a sampling pump 806, and a sample switching valve 804. The sample switching valve 804 switches between a concentration mode and a sensing mode. The embodiment of FIG. 8A depicts the valve 804 in the concentration mode. The concentration mode comprises an intake air stream 810 flowing through the preconcentration tube 402 in a first direction (e.g. left to right in FIG. 8A), and the sampling pump 806 sending a dilute sample 812 through a GC unit 308 comprising the first and second GC columns GC1, GC2.

Referring to FIG. 8B, an embodiment is illustrated with the apparatus 800 in the desorption flow regime. The valve 804 is directing flow from the pump 806 reversed through the preconcentration tube 402. Note that the valve 804 has shut down the flow from the pump 806 through the carrier flow restriction to the GC unit 308, although the physical connection of the valve 304 to that flow channel is not shown in FIG. 8B to prevent cluttering the Figure. The sample 310 gas flows through a tube shut flow restriction 906 to the valve 804 and through the preconcentration tube 402, while the pump 806 flow that went to the GC unit 308 is redirected to the valve 804 through a sample flow restriction 88. Therefore, in one embodiment of the desorption mode, the preconcentration tube 402 is desorbing sample gas to the GC unit 308.

In one embodiment, FIG. 8B depicts the valve 804 in the sensing mode. The sensing mode comprises an intake air stream 814 flowing through the preconcentration tube 402 in a second direction (right to left in FIG. 8B), and the sampling pump 806 sending a concentrated sample 816 through the GC unit 308.

FIG. 9 is a schematic block diagram illustrating one embodiment of an apparatus 1000 to uniformly heat a GC column GC1 in accordance with the present invention. The apparatus 1000 may comprise a heater element 1102. The heating element 1102 may comprise a heating element 1102 with a higher wattage rating than the required wattage to heat the GC column GC1 from the lowest predicted ambient temperature 202 to the highest GC target temperature 206. Such a design allows the heating element 1102 to provide the heat required for the sensor at a lower current and heating element 1102 temperature than a minimally specified heating element would. Such a design minimizes the potential for heat spikes and non-uniformity throughout the GC column GC1.

The apparatus 1100 may further comprise insulation 1104 between the heating element and the GC column GC1. The insulation 1104 further reduces the occurrence of temperature variability induced in the GC column GC1 by the heating element 1102.

FIG. 12A is a schematic block diagram illustrating one embodiment 1200 of slot 1204 machined into the sensor body 1202 for packing a preconcentration material in accordance with the present invention. The slot 1204 may be machined vertically into the sensor body 1202 and the apparatus 1200 may comprise a slot 1204 machined into the sensor body 1202, with a tube inserted into the slot, wherein the apparatus 1200 is packed into the tube.

Referring to FIG. 12B, the slot may be packed by inserting a slurry comprising microspheres and adhesive to form a uniformly porous plug 1206 at a first end of the slot 1204, and packing in the preconcentration material 1208. The apparatus 1200 may be completed by inserting a slurry to form a uniformly porous plug 1206 at a second end of the slot 1204. Referring to FIG. 12C, it may be desirable to offset the preconcentration material 1208 from the adhesive slurry 1206. Therefore, the apparatus 1200 of FIG. 12C shows the preconcentration material 1208 separated from the adhesive slurry 1206 by a pair of offset rods 1210 configured to offset the preconcentration material 1208 the desired distance.

The adhesive slurry may comprise glass microspheres. The adhesive may comprise an epoxy glue comprising 10% or less by weight of the slurry. The glass-glue mixture provides a consistent pressure drop once evenly mixed.

FIG. 13 is an illustration of sampling data 1300 shown in constant time, in accordance with the present invention. The example data labeled Chem 1 may be a typical elution peak for a relatively fast-eluting chemical, and the example data labeled Chem 2 may be a typical elution peak for a relatively slow-eluting chemical. Note that the time scale for FIG. 13 is relative only, and that the differences between the fast-eluting and slow-eluting chemicals are compressed to demonstrate the similarity effect and relative peak shapes. In practice, chemicals with elution peak widths that vary as much as those shown in FIG. 13 will often, but not necessarily, exhibit much greater separation in the time axis.

The fast eluting chemical may comprise a sharp peak as shown, and a relatively small number of sample points. The slow eluting chemical may comprise a flattened peak as shown, and a relatively large number of sample points. The area under the peaks is similar in the examples, as evidenced by the similar final values of the integration curves, indicating that these two chemicals were in the sample at approximately the same concentrations. The differences in the peak widths
and the number of samples in each peak may complicate the use of a modified Z-transform in analyzing GC sensor 102 signals.

FIG. 14 is an illustration of sampling data 1400 shown in constant log time, in accordance with the present invention. For purposes of illustration, the same example data from FIG. 13 is shown in FIG. 14, and therefore the time axis differences between the fast and slow eluting chemicals may likewise be compressed in FIG. 14. The fast eluting chemical may comprise a sharp peak as shown. The slow eluting chemical may comprise a similarly shaped peak in constant log time. The peaks for the fast and slow eluting chemicals in FIG. 14 may exhibit similar numbers of sample points within each peak. Note that the integral curves in FIG. 14 are generated with a rectangular estimate, and that close observation of the integral curves in FIG. 14 illustrates that although the fast and slow eluting chemicals had the same area under the curve in constant time sampling, they are not at exactly the same area under the curve in constant log-time sampling, although the introduced error is small.

FIG. 15 is an illustration of sampling data adjusted with a plurality of noise suppression methods in accordance with the present invention. The first data set 1502 may show a data set adjusted by a first noise suppression method, the second data set 1504 may show a data set adjusted by a second noise suppression method, and the third data set 1506 may show a data set adjusted by a third noise suppression method. In one embodiment, the noise-filtering module 116 may label a peak at about 15 time units as data because this peak occurs in all three sets 1502, 1504, 1506. The noise-filtering module 116 may label peaks at about 45, 65, 75, 90, and 130 time units as noise because these peaks appear on only some of the sets 1502, 1504, 1506. Further, the noise-filtering module 116 may label a peak at about 115 time units as data because this peak occurs in all three data sets 1502, 1504, 1506. The noise suppression methods may be noise suppression wavelets.

The schematic flow chart diagrams included herein are generally set forth as logical flow chart diagrams. As such, the depicted order and labeled steps are indicative of one embodiment of the presented method. Other steps and methods may be conceived that are equivalent in function, logic, or effect to one or more steps, or portions thereof, of the illustrated method. Additionally, the format and symbols employed are provided to explain the logical steps of the method and are understood not to limit the scope of the method. Although various arrow types and line types may be employed in the flow chart diagrams, they are understood not to limit the scope of the corresponding method. Indeed, some arrows or other connectors may be used to indicate only the logical flow of the method. For instance, the arrow may indicate a waiting or monitoring period of unspecified duration between enumerated steps of the depicted method. Additionally, the order in which a particular method occurs may or may not strictly adhere to the order of the corresponding steps shown.

FIG. 16 is a schematic flow diagram illustrating one embodiment of a method 1600 to manufacture a GC column GC1, GC2 in accordance with the present invention. The method 1600 may be performed with a torsion spring making machine configured to manage materials of the diameter of the GC column GC1, GC2. The method 1600 may begin with bending 1602 a tube of slightly longer than the desired GC column length into a GC column GC1, GC2. Then, the tube may be crimped 1604 at the ends to facilitate maintaining tube cleanliness during storage 1606 and/or transport 1606 of the column GC1, GC2. Then method 1600 may continue with a practitioner cutting 1608 off the ends of the column GC1, GC2 and installing 1610 the column GC1, GC2 into a GC sensor 102.

FIG. 17 is a schematic flow diagram illustrating one embodiment of a method 1700 to utilize an internal standard chemical in a GC sensor 102 in accordance with the present invention. The method 1700 may begin with packing 1702 a preconcentration material 1208 into a GC sensor. The preconcentration material 1208 may comprise a known material, for example Tenax, that releases a known byproduct at a set temperature. The method 1700 may proceed with heating 1704 the preconcentration material 1208 to a specified temperature at which the known byproduct is released. The controller 104 may then track 1706 the elution of the known byproduct, and compare 1708 the elution time to a known standard elution time according to the temperature of the GC columns GC1, GC2.

FIG. 18 is a schematic flow diagram illustrating one embodiment of a method 1800 to pack a preconcentration material 1208 in accordance with the present invention. The method 1800 may begin with an practitioner mixing 1802 a microsphere-adhesive slurry and placing 1804 some of the slurry at one end of a slot 1204. The practitioner may then insert 1806 an offset rod into the slot to position a preconcentration material in the slot 1204. The practitioner may then pack 1808 a preconcentration material into the slot, and insert 1810 another offset rod into the slot. The practitioner may then fill the slot 1204 with microsphere-adhesive slurry to complete the packing of the preconcentration material.

FIG. 19 is a schematic flow diagram illustrating one embodiment of a method 1900 to control the temperature of a GC column GC1, GC2 in accordance with the present invention. The method 1900 may begin 1902 with the controller storing 1904 a set of elution versus temperature data for a number of chemicals of interest. The temperature control module 1906 may be configured to detect 1904 the ambient temperature 202, and to select 1906 a target temperature 206 for the GC column(s) based on the ambient temperature 202 and the elution versus temperature data 204. The temperature control module 1906 may be further configured to heat 1908 the GC column(s) GC1, GC2 to the target temperature 206.

FIG. 20 is a schematic flow diagram illustrating one embodiment of a similarity sequencing sample data acquisition method 2000 in accordance with the present invention. The method 2000 may begin with the similarity sequencing module 112 determining 2002 whether a variable time step sampling rate is available. Where variable time step sampling is available, the similarity sequencing module 112 may collect 2004 data in a constant log-time step, wherein each data point proceeds at the time value t, where:

\[ t = \frac{2}{A} e^{-k} \]  

\begin{equation}
\text{Equation 3.}
\end{equation}

In Equation 2, s is the sample number to be taken, and t is the normal time at which the sample is taken. The value k determines the distance between sample increments, while the value A is used to define the time at which the first sample is taken. For example, the value k may be 0.2, and A may be 1. In the example, the first sample is taken at approximately 1.22 seconds, the second sample at 1.49 seconds, and another sample is taken at each 0.2 log-seconds. In the example, the 20th sample would be taken at about 54.6 seconds.

Where variable time step sampling is not available, the similarity sequencing module 112 may collect 2010 data in a constant normal-time step, and process 2012 the data to simulate constant log-time steps.

The method 2000 may proceed with the similarity sequencing module 112 storing 2006 the sample data, and the
controller 104 may make 2008 the stored data available to a signal processing algorithm on the signal processing module 114.

FIG. 21 is a schematic flow diagram illustrating one embodiment of a method 2100 for analyzing sampling data in accordance with the present invention. The method 2100 may begin with the signal processing module 114 receiving 2102 sample data 216 which may be sequenced by the similarity sequencing module 112. The signal processing module 114 may receive 2104 a system characterization which may comprise a Z-transform transfer function of the system 100. The signal processing module 114 may deconvolute 2106 the sample data 216 with the largest polynomial division that does not produce a negative response and induce instability. The signal processing module 114 may then determine the input signal according to Equation 2.

FIG. 22 is a schematic flow diagram illustrating one embodiment of a method 2200 for identifying data peaks and noise peaks in a set of sampling data 216 in accordance with the present invention. The method 2200 may begin with the noise filtering module 116 receiving 2202 sample data 216. The noise filtering module 116 may then apply 2204 a plurality of noise suppression wavelets 222 to the sample data 216. The noise filtering module 116 may then generate 2206 a set of data peaks, and identify 2208 shifting peaks as noise, and stable peaks as signal or data.

FIG. 23 is a schematic flow diagram illustrating one embodiment of a method 2300 for low cost high resolution chemical detection in accordance with the present invention. Some steps of the method 2300 may be implemented by a controller 104. The method 2300 includes providing 2302 a first outer sealing body 1008 and a second outer sealing body 1010. The method 2300 further includes etching 2304 a plurality of flow channels into the first outer sealing body 1008 and a second outer sealing body 1010. The method 2300 continues with providing 2306 a first GC column GC1 and a second GC column GC2 and further providing 2308 a valve 408 that switches between a first flow regime and a second flow regime. The method 2300 includes operating 2310 the valve in the first flow regime by flowing a sample through the first and second GC columns GC1, GC2, and operating 2312 the valve in the second flow regime by flowing a sample through the second GC column GC2 without flowing the sample through the first GC column GC1.

The method 2300 further includes flowing 2314 an intake air stream through a preconcentration tube 402 in a first direction to concentrate chemicals on the tube 402, and flowing 2316 the intake air stream through the preconcentration tube 402 in a second direction to deliver a concentrated sample to a GC unit 308. The method 2300 may further include heating 2318 the preconcentration tube 402 to a specified temperature, thereby releasing a known chemical from preconcentration material in the preconcentration tube 402, and detecting elution of the known chemical from the GC unit 308. The method 2300 may further include providing a detector circuit 316 interposed between the first and second outer bodies 1008, 1010, providing a detector circuit seal, and further providing a pressure equalizing channel from a sample channel to the detector circuit 316.

The present invention may be embodied in other specific forms without departing from its spirit or essential characteristics. The described embodiments are to be considered in all respects only as illustrative and not restrictive. The scope of the invention is, therefore, indicated by the appended claims rather than by the foregoing description. All changes which come within the meaning and range of equivalency of the claims are to be embraced within their scope.

What is claimed is:

1. An apparatus for high resolution chemical detection, comprising:
   a first outer sealing body and a second outer sealing body;
   a plurality of flow channels etched into the first outer sealing body and the second outer sealing body;
   a first gas chromatography (GC) column and a second GC column interposed between the first and second outer sealing bodies;
   and a valve that switches between a first flow regime and a second flow regime, wherein the first flow regime comprises a sample flowing through the first GC column then the second GC column, and wherein the second flow regime comprises the sample flowing to the second GC column without flowing through the first GC column.

2. The apparatus of claim 1, wherein the valve is a solenoid valve.

3. The apparatus of claim 1, further comprising a first pump, a first resistance, a second resistance, and a third resistance, wherein: the first flow regime further comprises a first fluid stream from the first pump that flows through the first GC column and the second GC column, and a second fluid stream directed by the valve that flows through the second resistance and the first resistance; and the second flow regime further comprises a third fluid stream from the first pump that flows through the first GC column and the first resistance, and a fourth fluid stream directed by the valve that flows through the second pump that flows through the second GC column, wherein the fourth flow stream further prevents the third fluid stream from flowing through the second GC column.

4. The apparatus of claim 1, further comprising a first pump and a second pump, and a first resistance, wherein: the first flow regime further comprises a first fluid stream from the first pump that flows through the first GC column and the second GC column, and a second fluid stream directed by the valve from the second pump that flows through the first resistance, wherein the second stream further prevents the first stream from flowing through the first resistance; and the second flow regime further comprises a third fluid stream from the first pump that flows through the first GC column and the first resistance, and a fourth fluid stream directed by the valve from the second pump that flows through the second GC column, wherein the fourth flow stream further prevents the third stream from flowing through the second GC column.

5. The apparatus of claim 1, further comprising a first pump, a first resistance, and a fourth resistance, wherein: the first flow regime further comprises a first fluid stream from the first pump that flows through the first GC column and the second GC column, and a second fluid stream directed by the valve that flows through the fourth resistance and the first resistance; and the second flow regime further comprises a third fluid stream from the first pump that flows through the first GC column and the first resistance, and a fourth fluid stream directed by the valve that flows through the fourth resistance and the second GC column, wherein the fourth fluid stream further prevents the third fluid stream from flowing through the second GC column.

6. The apparatus of claim 5, wherein each resistance comprises a flow resistor selected from the flow resistors consisting of an orifice, a controllable valve, and a microboard with porous substrates.

7. The apparatus of claim 1, wherein at least one of the plurality of flow channels further comprises an impermeable insert interposed between the first and second outer sealing bodies.
8. The apparatus of claim 7, wherein the impermeable insert comprises one of a quartz insert and a ceramic insert.

9. The apparatus of claim 8, further comprising a detector circuit that detects a target chemical eluting from the first and second GC columns, wherein the target chemical occurs in an ambient environment at less than about 1,000 parts-per-billion.

10. The apparatus of claim 1, further comprising a preconcentration tube, a sampling pump, and a sample switching valve, wherein: the preconcentration tube comprises a preconcentration material that adsorbs and desorbs chemicals from an intake air stream; and the sample switching valve switches between a concentration mode and sensing mode, wherein the concentration mode comprises the intake air stream flowing through the preconcentration tube in a first direction, and a the sampling pump sending a dilute sample through a GC unit comprising the first and second GC columns, and wherein the sensing mode comprises the intake air stream flowing through the preconcentration tube in a second direction, and the sampling pump sending a concentrated sample through the GC unit.

11. The apparatus of claim 10, wherein the preconcentration material releases a known chemical at a specified temperature, the apparatus further comprising an internal standard delivery module configured to heat the preconcentration material to the specified temperature, and a calibration module configured to detect elution of the known chemical from the GC unit.

12. The apparatus of claim 11, wherein the preconcentration material comprises an adsorbent resin.

13. The apparatus of claim 1, further comprising a detector circuit interposed between the first and second outer sealing bodies, wherein the detector circuit comprises a detector circuit seal, and wherein the apparatus further comprises a pressure equalizing channel configured to equalize a first pressure in a sample channel with a second pressure in the detector circuit.

14. The apparatus of claim 13, further comprising at least one spring interposed between the first and second outer sealing bodies, wherein the at least one spring applies force to enhance the detector circuit seal.

15. A method for high resolution chemical detection, comprising:

- providing a first outer sealing body and a second outer sealing body; etching a plurality of flow channels into the first outer sealing body and the second sealing body; providing a first gas chromatography (GC) column and a second GC column interposed between the first and second outer sealing bodies; providing a valve that switches between a first flow regime and a second flow regime; operating the valve in the first flow regime by flowing a sample through the first GC column and then the second GC column; and operating the valve in the second flow regime by flowing the sample through the second GC column without flowing the sample through the first GC column.

16. The method of claim 15, further comprising flowing an intake air stream through a preconcentration tube in a first direction to concentrate chemicals on the preconcentration tube, and flowing the intake air stream through the preconcentration tube in a second direction to deliver a concentrated sample through a GC unit comprising the first and second GC columns.

17. The method of claim 16, further comprising heating the preconcentration tube to a specified temperature thereby releasing a known chemical from the preconcentration tube, and detecting elution of the known chemical from the GC unit.

18. The method of claim 15, further comprising providing a detector circuit interposed between the first and second outer sealing bodies, and providing a detector circuit seal.

19. The method of claim 18, further comprising providing a pressure equalizing channel from a sample channel to the detector circuit.

20. A gas-chromatography sensor comprising: a first outer sealing body and a second outer sealing body; a plurality of flow channels etched into the first outer sealing body and the second outer sealing body; a first gas chromatography (GC) column and a second GC column interposed between the first and second outer sealing bodies; a valve that switches between a first flow regime and a second flow regime, wherein the first flow regime comprises a sample flowing through the first GC column then the second GC column, and wherein the second flow regime comprises the sample flowing to the second GC column without flowing through the first GC column, and a preconcentration tube, a sampling pump, and a sample switching valve, wherein: the preconcentration tube comprises a preconcentration material that adsorbs and desorbs chemicals from an intake air stream; and the sample switching valve switches between a concentration mode and sensing mode, wherein the concentration mode comprises the intake air stream flowing through the preconcentration tube in a first direction, and the sampling pump sending a dilute sample through a GC unit comprising the first and second GC columns, and wherein the sensing mode comprises the intake air stream flowing through the preconcentration tube in a second direction, and the sampling pump sending a concentrated sample through the GC unit.

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